

စာတမ်း

အကြောင်း

အကြောင်း

အကြောင်းအရာ:

(DDU-1000) အားဖြင့် အားဖြင့်

(Conductive-atomic force microscopy, C-AFM) အားဖြင့်

(NSOM) အားဖြင့်

2-1

2-1-1 B (phase change) အားဖြင့်

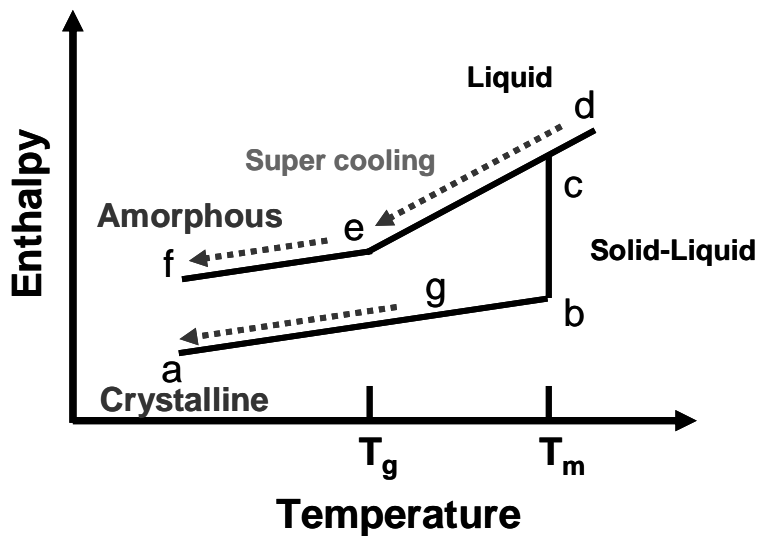
(အားဖြင့်) 1968 ခု - S.R.Ovshinsky^[27] အားဖြင့်

, (Chalcogenide) အားဖြင့်

အားဖြင့်

GeSbTe ။ AgInSbTe အားဖြင့်

အားဖြင့်



2.1 B (Enthalpy)

အားဖြင့်

temperature) ။ T_m (melt temperature)

အားဖြင့်^[29] အားဖြင့်

g (glass transition

a-b-c-d အားဖြင့်

Cx%00 d-e-f x3Zp(2 amorphous)
 x3ö f-e-g-a 0xxHKáúxòBHö

ÖöBö (T_m)

HknBñ3

mEH%I²

OÖKZö (quench)KQ

HÁFZbE

Öö 2.1 KQOÖ

Q² Enthalpy Áö Áö H=U+PVö U Á

P Á V ÖH)H²ö

0 Ú h ì ÜÖ6 2' B i Q 0 " šâ Äc

dH=dU+PxdV+VxdPö dQ=dU+PxdVö dH=dQ+VxdPö

Bİ3xbÖk3pâ

BİBk3E (Latent Heat)Ü 2.1 ' b-c

ö

Ö'Ö (Gibbs free

energy)Ö Ö G=U-TS+PVö S Á (entropy)ö TÁ

Kp"JU 2.2ÖH? ΔG ÖÜ

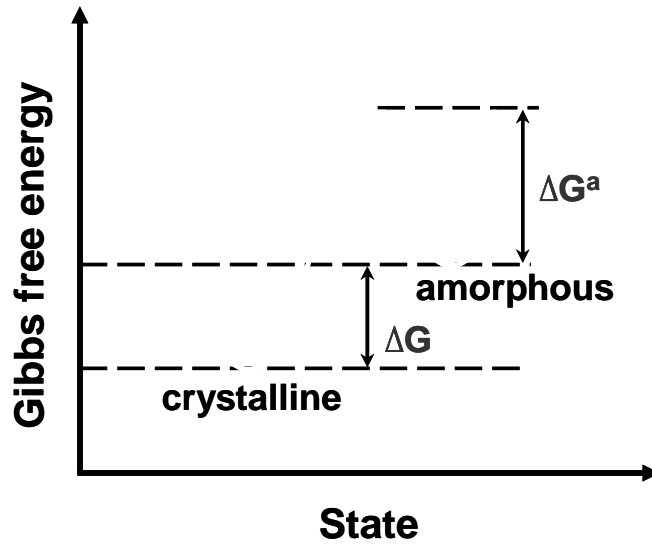
òBÄ ΔG_a ÖB (potential barrier)ö ΔG_a '

nÖÖ ΔG_aÖ

ÉÁ ΔG_a µHÖ

šBöBöpâ ΔG_a Ó

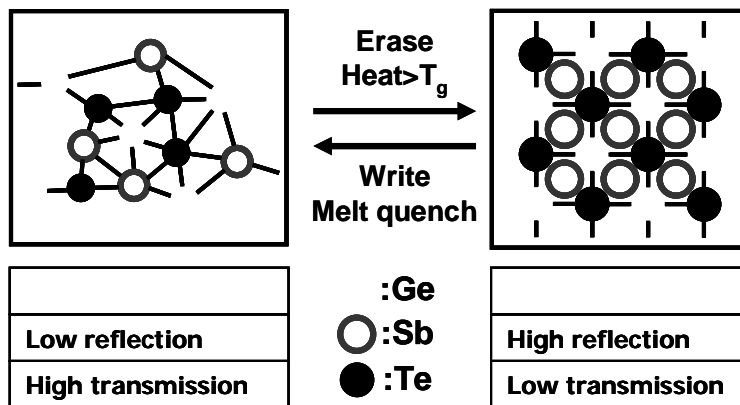
WÖKOW(Kö



2.2 H₂ (Gibbs free energy)

60

2-1-2 B₂O₃



Ú 2.3 H₂, Ú

B₂O₃

H₂ (Crystalline state)

(Amorphous state)

2.3 QpHH, B₂O₃

H₂ h₂ö-

ÖxÖö

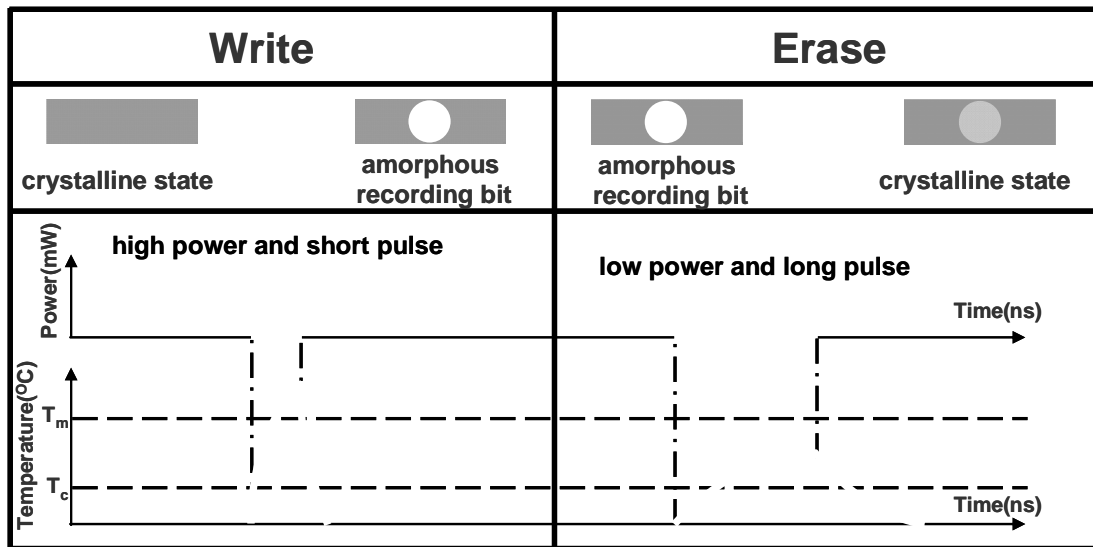
ÖöÖÖ

"xpkÖpkÖpkÖ

šÖÖÖ

ÖÖÖÖ

(erase) 2.4



Ú 2.4

ĐW

ĐW

ĐW

ĐW

Yú (melting point)

(quench)

ĐW

ĐW

ĐW

(Yde'

K)ĐnYeĐ,ĐKpĐ

ĐqĐÁĐ

! ← ĐhĐWĐĐ

ĐkĐWĐ

H,yĐĐ

ĐĐĐĐ

Đ

ĐĐ

ĐĐWĐĐ

ĐGĐĐWĐ

2.56 DW

(write power)g

W (erase power)gDW

(read power)pk

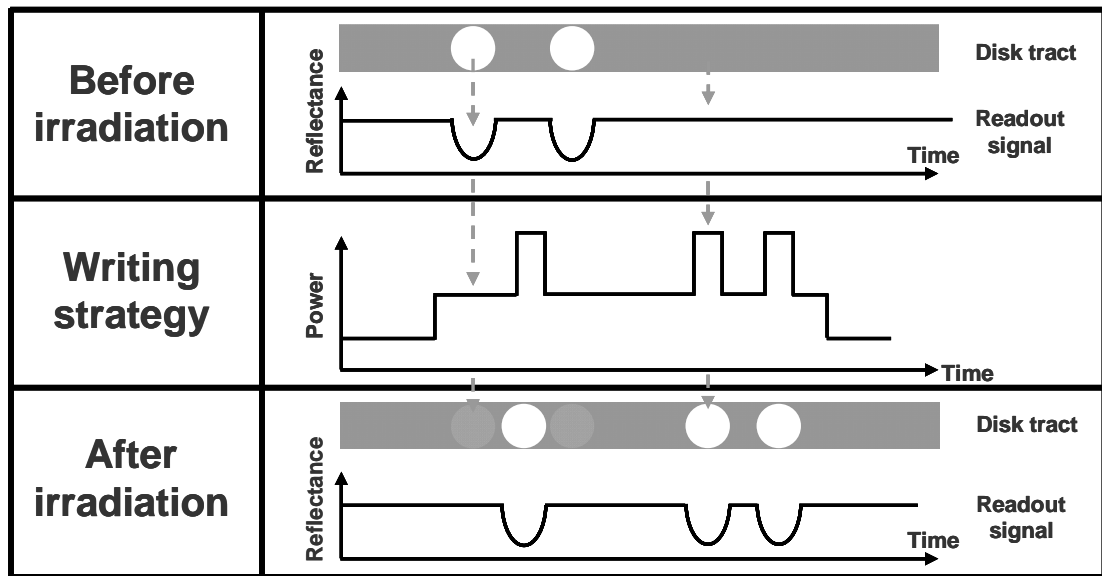
QDW(B

W

-Bp

B"Xp

A



2.5 (Direct overwrite method

recording)

[28]

2-1-3 BWH!

A>wH

BFFW

H

2.6H, QyAQ

B

B"BS"

SPUTTER

B

(polycarbonate)wH

ywE bonding

iDVD

A"



Ü 2.6 BÄKH,Ü

!

! B (A) Protection layer

30

/DW-30cBpkb"65",p[

Bpká6B

ZnS-SiO₂(oÁ0:20)

Á-

ZnSn%

SiO₂ÖRQ0b46

ÁBæ

(1)xi8

(2)Ñ

ó (3)H,00BöBbD

(4)eä

xSpkxBKZCÖ0ZC(

(erase)

Wö

pk wk(Y

Ö

/ÄasZpêYÜsheDW

H8V0r%(D

[30]ÖmW

Ö [31]Ö,ÉYD,ÖpBö

BÄÜKÖÖÜ

Et Al-Tiõ Al-Crõ Al-Taõ Auõ Agõ
 -
 (1) 85õ (2) (3)
 "w"
 6

2-2

51Hqg.z

(RITEK) DVD+RW(4X)Xpð

"óH,óB:

(DDU-1000)p¼

úÆ

2-2-1

(óB:

DDU-1000)Aß

qwbUCpwj'

00VÆ

ôäköö

(Photo-detector)

xôôK,4

lö

iXpW6B&E

48dB 0wð

(Carrier to Noise Ratio, CNR) e-

10% 00W

(Jitter)ð

È.0q

(CNRj 48dBù Jitteri 10%)0U.zX

p" DVD+RW ið

(CNR) Æ

PULSTEC

æ "b ô úB DVD±R/±RW

Ú@ ô &Á

DDU-1000 X" Aß&BZù

2.7

0Aß,0Ô

(Oscilloscope)ð

bÔ (Signal generator)ð

Pulse generator)ð

ð

KÔ (Signal analyzer)ð:

(Spectrum analyzer)wð

o (Disc driver box)ð

(Laser diode controller) ð

§Ó_H 0 ÷ÚÆ: Ô" ô Á" 'Èù

DVD±R/±RW Aß&BZù

(CNR) 0.5

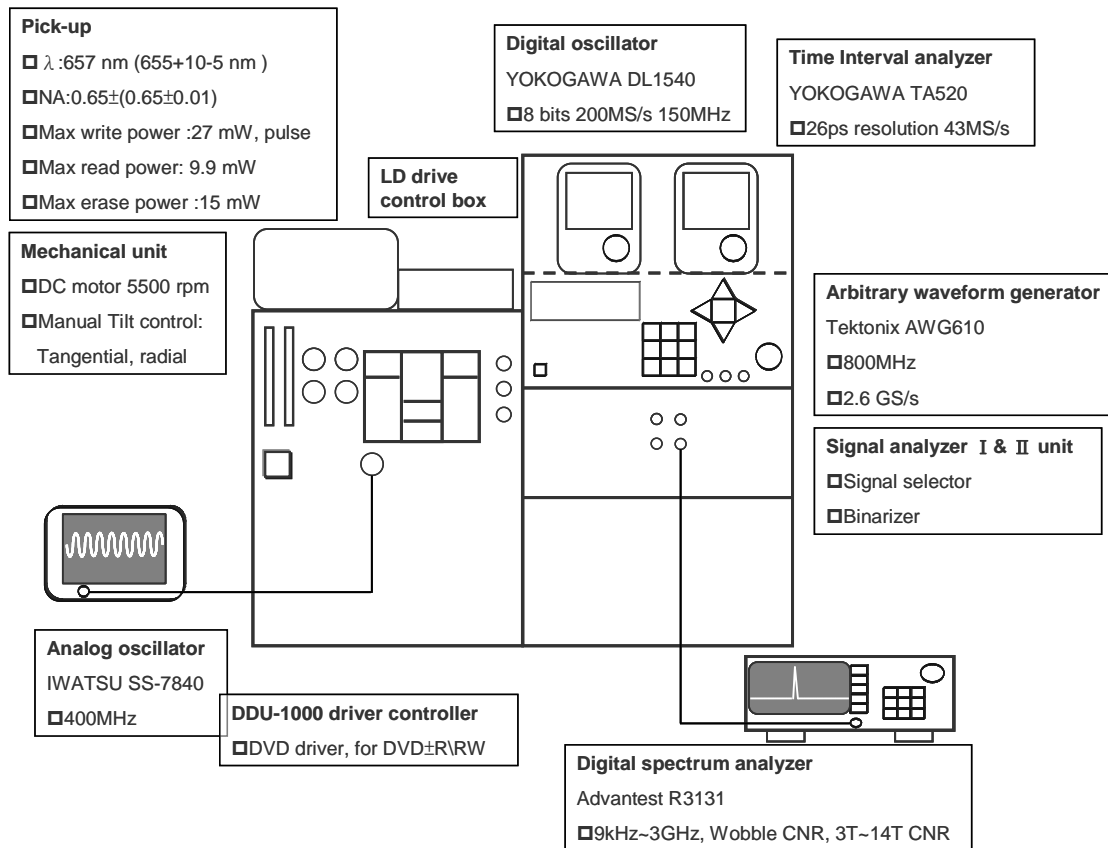
(Land / Groove)

K (Wobble) 0.05 W (Jitter)

0.3T~14T

Eye pattern 0.5

0



2.7

0.5

0.3

0.05

0.5

0.5

0.5

(Pulse generator) 0.5

0.5

πύξ (Mark size)



$$\frac{(1T \sim 28T) \times CLV}{2 \times Frequency} = \text{Mark size}$$

πύξ (Mark size)

3T:Á

μύξ (Constant Angle Velocity, CAV)

(Constant Angle Velocity, CAV)

(Constant Linear

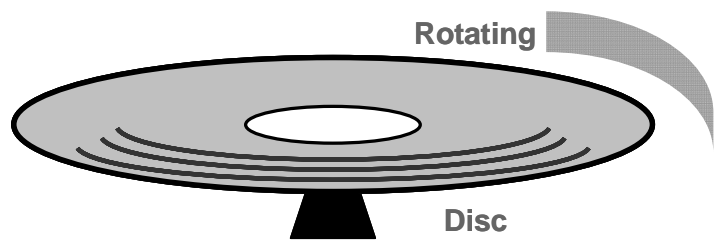
Velocity, CLV)

μύξ (Mark size)

μύξ (Mark size)

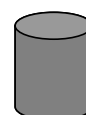
(Disc driver box)

ø



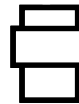
Objective

Beam Splitter



Detector

Matching Lens



Laser diode

ø

μύξ (Mark size)

μύξ (Mark size)

μύξ (Mark size)

μύξ (Mark size)

(Photo-detector)

2-2-2 (6:*

(Atomic force microscopy, AFM)

(Conductive atomic

force microscope, C-AFM) C-AFM,

ö

•dM I " ' dM μ ,—

Veeco æ @ ô &

DI-3100 AFM AFM Ö (1)

x{ (contact mode) ö (2) (non- contact mode) (3)ø

(tapping mode) 1-2-2

(1) (2)

(3)s" (Lithography)..

"p

DVD+RWB

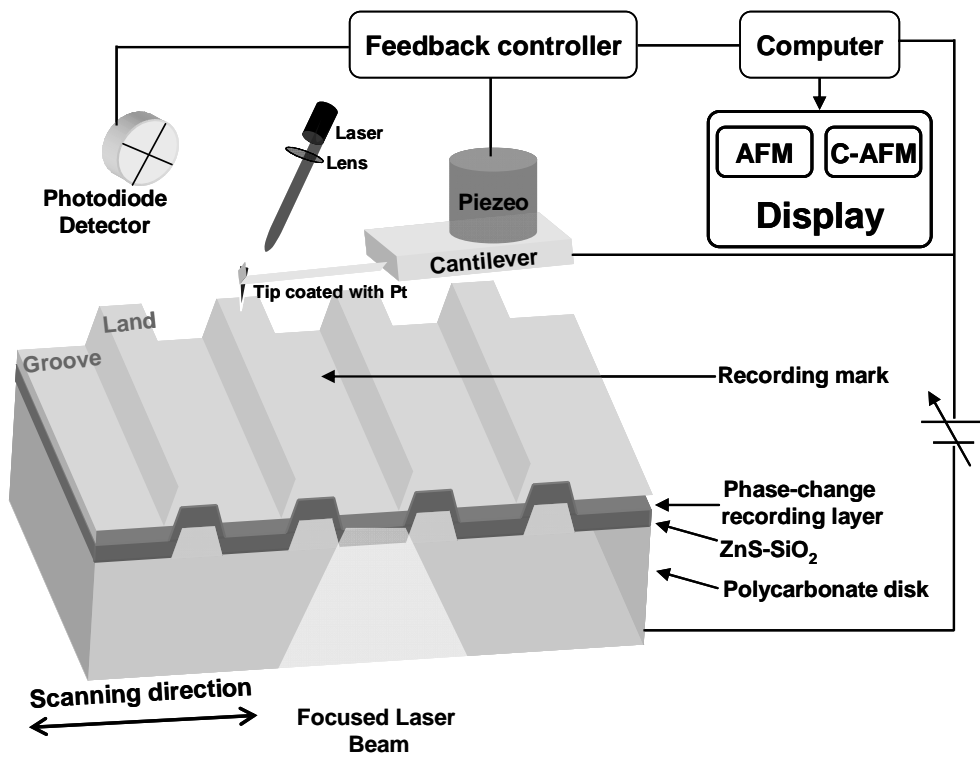
NSOMy

2.9m Photodiode detector*

Á

Ex

DVDwH



Ø.9 5MŽ

Ä. 10.ÄS

(Colloidal Silver Paste) 600E

"GHO (Pt) 60x6

OE(Pt)KÁ 20 1/5

C-AFM 3000 70Ä

6000

fCC C-AFM 110

ä šš > : (DI-3100) B' -Ä' äy 1/2

(C-AFM) 600

600

600).p.Cø

(-)

)éöó•

0ç C-AFMúTqñfTqä

KāqnñYqç

C...QpÁY

TqD DCpÁfTqö

2.10ö

-CññE

ö

RİTEK DVD+RW(4X)BñDDDU-1000

ö

μW öñkñT qéI”...CñDCö

2.10(a)ö

2.10(b)Á

C-AFMyññCç

ñññ

ñññ

[]Q0.qñkñHö

(a) C-AFM

(b) C-AFM

Ü 2.10 (a)C...CñE
C-AFM yññ

500nm

500nm ö(b)

CDCñE

500nm

500nm öö

2-3 **■**: (NSOM)Ž

U "MI": Ć

NTMDT æ @

Solver SNOM Ć Ć Ć Ć Ć

Ć (Topography)

Ć Ć Ć Ć Ć

(NSOM) Ć Ć

l" Ć Ć

"Jš

(Shear force)" Ć

(1) Ć Ć

O Ć

(2) Ć Ć

(3) Ć Ć Ć

: Ć

(4) M" Ć Ć

(5) Ć Ć Ć Ć

3 Ć Ć Ć

2-3-1 Ć Ć Ć

h Ć Ć Ć

[32] (Piezoelectric) Ć Ć Ć Ć

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[33] Ć Ć Ć

Ć Ć

Ć Ć Ć Ć

Ć Ć Ć Ć

" Ć

" Ć

6 M" Ć Ć (Tuning fork)

Ć

Ć Ć Ć

(Quartz wafer) Ć Ć Ć

Ć Ć Ć Ć

2.11 Q

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Ć Ć Ć Ć

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(Ć Ć

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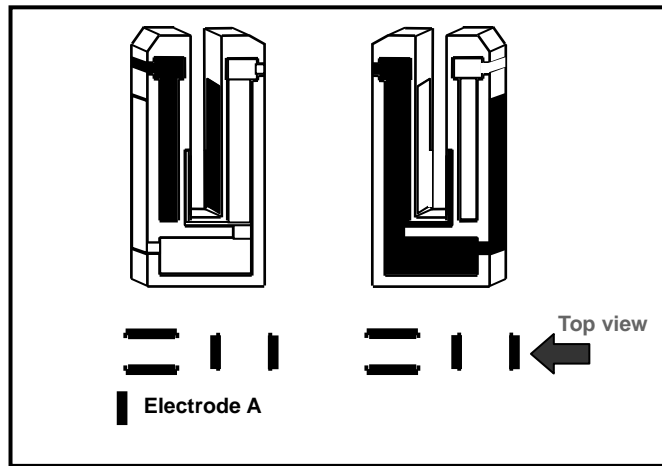
O Ć Ć Ć Ć Ć Ć Ć

(nature resonance

frequency)

(wafer)

δ



Ú 2.11

6M

101 kHz

2.12

z

(fiber)

0A

Shear force

(function generator)

α

Δ

Q

(5~10 ¼)

8

6

0 μ

iō

U2.12 ± 8 KDS3H)U'

2-3-2

D. W. Phol^[34]

4;s"0

„ (tip)0¼

(nm)é

0p ¼H,p 0

ix3x-D0Y

K0† 200 16U E. Betzig^[35]„t0

B. (Micro-pipette) pX 0E

k0(AI) 0b 0H,0U

0AB00000

0 100 1000

0000µ 10⁻⁵ pS0 1980 R. C.

Reddick h 0s" 0000

I> (Photon Scanning Tunneling Microscope-PSTM)^[36]0

hI" 000

Đ.Đ.Đ.Đ.Đ

Đ.Đ.Đ.Đ.Đ (ođ :đ (HF)Đ.Đ.Đ.Đ.Đ

Đ.Đ.Đ.Đ.Đ

Đ.Đ.Đ.Đ.Đ

xĐ.Đ

Đ.Đ.Đ.Đ.Đ

Đ.Đ.Đ (single mode)đ (core)Đ.Đ.Đ 3.7! (μm)đ

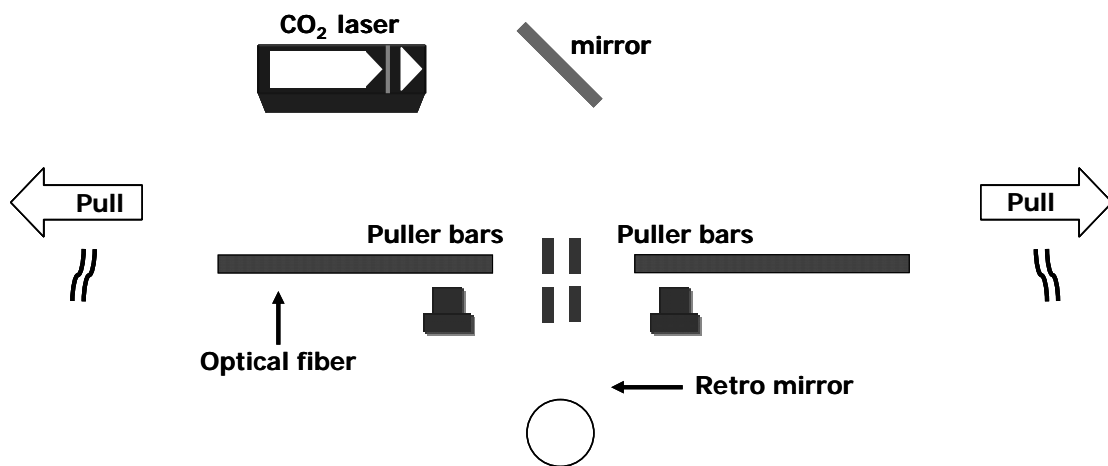
Đ.Đ.Đ

Đ.Đ.Đ (CO₂ laser)Đ.Đ.Đ.Đ.Đ

Đ.Đ.Đ Đ.Đ.Đ.Đ.Đ

Đ.Đ.Đ.Đ.Đ

Đ.Đ.Đ.Đ.Đ 2.13 đ



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Đ.Đ.Đ.Đ.Đ

Đ.Đ.Đ.Đ.Đ

40 Đ.Đ.Đ

: (Al)δ (Au)ϵ (Pt)ϑ"100'

À (confine)ϵΓϑ

ϑVbPö

M;:δö

2.14 ø

ÀA üϵ

Uϑ:ϑOö

ρ (tip)ϑV3ϑ

ϑö

Á1hδé%AK

(skin depth)hJ

0Mϑbkö

Ù 2.14 δö

2-3-3 2.3.3:

2.3.3.1

2.3.3.1.1 (1) 2.3.3.1.2 (2)

2.3.3.1.1.1 AFM 2.3.3.1.1.2

AFM 2.3.3.1.1.2

2.3.3.1.1.1.1

2.3.3.1.1.1.1

2.3.3.1.1.1.2 AFM 2.3.3.1.1.1.3

2.3.3.1.1.1.2

2.3.3.1.1.1.3

(CNR),

2.3.3.1.1.1.4

2.3.3.1.1.1.4.1

2.3.3.1.1.1.4.2

2.3.3.1.1.1.4.2

2.3.3.1.1.1.4.3

2.3.3.1.1.1.4.4

2.3.3.1.1.1.4.5

2.15 2.3.3.1.1.1.4.5

2.3.3.1.1.1.4.6

(Function generator) 2.3.3.1.1.1.4.6

2.3.3.1.1.1.4.7

2.3.3.1.1.1.4.7

2.3.3.1.1.1.4.8

(Function generator) 2.3.3.1.1.1.4.8

2.3.3.1.1.1.4.9

2.3.3.1.1.1.4.9.1

(Lock-in

2.3.3.1.1.1.4.9.2 Amplifier) 2.3.3.1.1.1.4.9.2

2.3.3.1.1.1.4.9.3 (Sub-wavelength) 2.3.3.1.1.1.4.9.3

2.3.3.1.1.1.4.9.4 (Controller system) 2.3.3.1.1.1.4.9.4

(Scanning head)

2.3.3.1.1.1.4.9.5

(Piezo tube) p

000

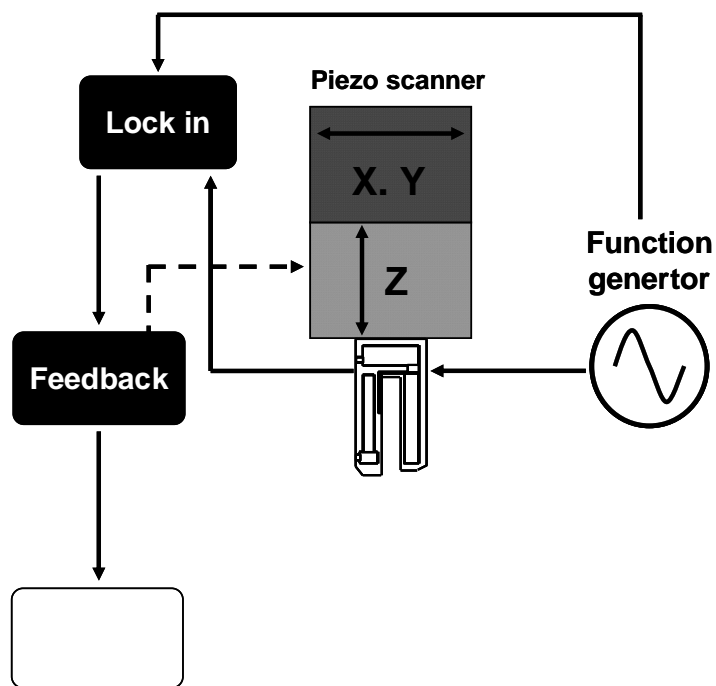
000

000

000

(AFM) V

(Topography)



Ú.15 JŠAFM

2-3-4

6511 M
 μ, NTMDT (NSOM)
 Solver P47
 À
 IÀ :
 > 632.8 (CW) 12
 mW, 500:1 W (1) (2) sIK/õ
 (3) Qb (4)

Neutral density filter)

b (i)
 B
 (Fiber coupler)
 A
 (Fiber
 coupler)
 Q
 0...
 A QSB x-y Ks}
 "ö

(Objective)

μW $40 \text{ m}\mu\text{s}$ (N.A.) $\times 0.6$
 (compensator) $\times 0.6$
 wHK: 6δ

! !
 $\times 2.16 \mu\text{s}$ (compensator) y μs [37] δ

(Compensator)

$6\mu\text{s} \dots 6\mu\text{s}$ $\times \text{wH}\delta$
 b $\frac{1}{2} \dots \delta$ $2.16 \mu\text{s}$

2.17 μs - $\times \text{H}\delta$

$\times \text{d}$; $\times \text{H}\delta$ $\times \text{p}\text{A}$ $\times \text{H}$
 $\times \text{K}\delta \times \text{Q}$ " δ

! $\times 2.17 \mu\text{s}$ $\times \text{H}\delta$ $\times \frac{1}{2}$ [38] δ

CCD (Charge couple device)

30% (640x480)

40 m (tip)

Dü

ÀZ... (PMT)

D E% > A E (s- nW) + μ ò û

& Controller

y + μ Ô (Lock-in amplifier)

M • Ô chapper É 0 r % D È -

chapper Q 0 Ô ô "Q 0 â W) ô ô

chapper U ô B Ô 5 W 0 y + μ Ô Lock-in

amplifier) 6 U — PMT A + μ Ô

+ μ Ô 5 W Ô Q 0 + W †

8 6 2

2-3-5

M Ô (fiber) ò i c A

ce x e % " : s p e

D I X " °

% b e g 6 \$ (ALTECO, SUPER GLUE) @

§ J D E P + ü

6-8 U Ô 0 " Ô B Ô ü

(Scanning head) $20 \times 20 \mu\text{m}$

ic $20 \times 20 \mu\text{m}$

(c) $20 \times 20 \mu\text{m}$

" $8 \times 8 \mu\text{m}$

Q v $20 \mu\text{m}$

MSA

-A

2.18

c $20 \mu\text{m}$

A (core) $20 \mu\text{m}$

(tip) $20 \mu\text{m}$

AZ...

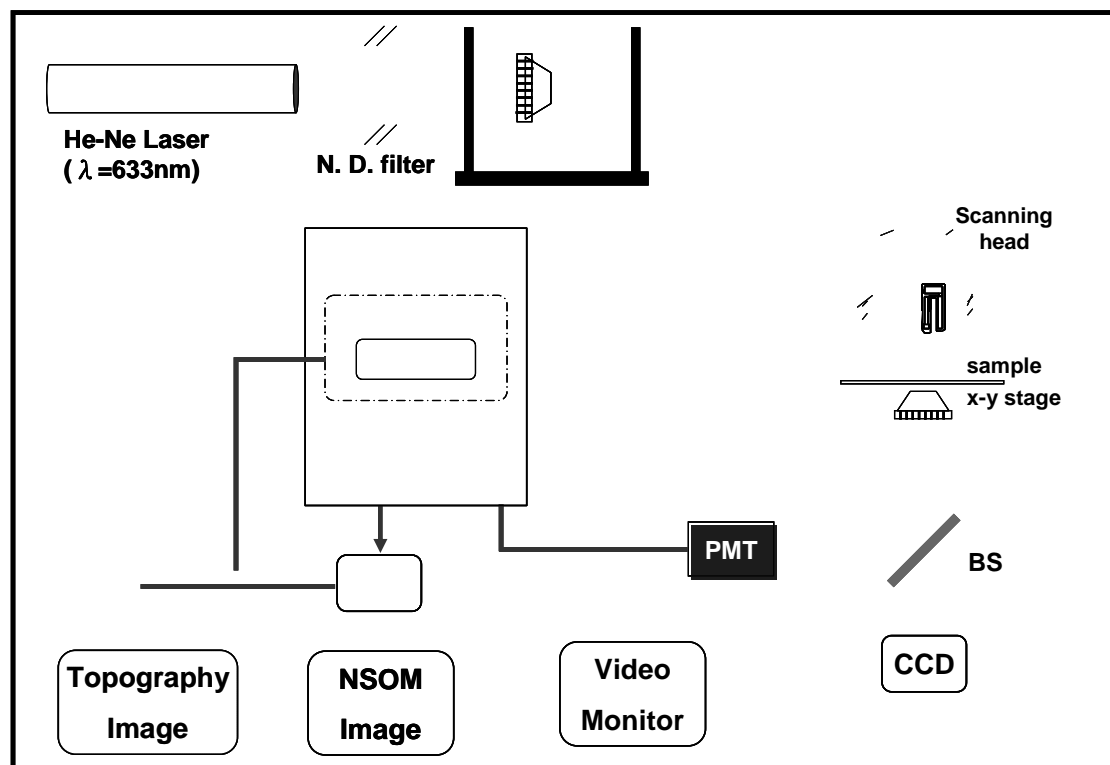
(PMT) $20 \mu\text{m}$

% Controller $20 \mu\text{m}$

A $1/2$

(NSOM) $20 \mu\text{m}$

NSOM $20 \mu\text{m}$



Ü 2.18 A

MZ

2.19

À

-05

2.19



chapter pSBœ

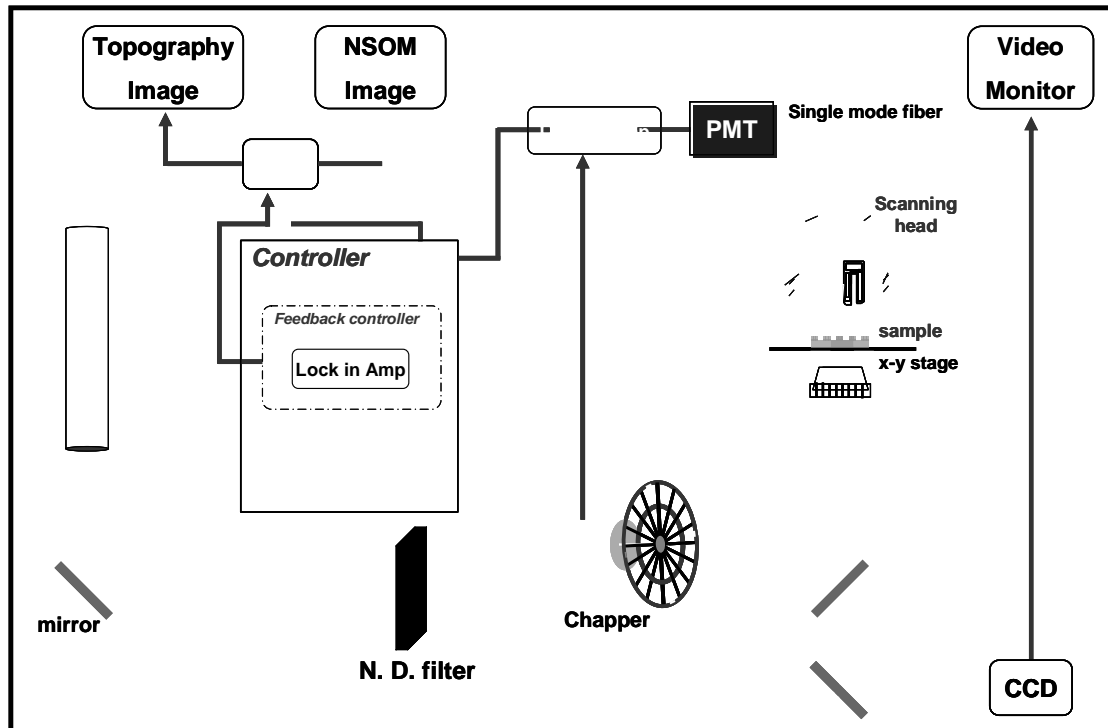


.. 0.1-µm

chapter 10



Controller (100%)



2.19 À

100%